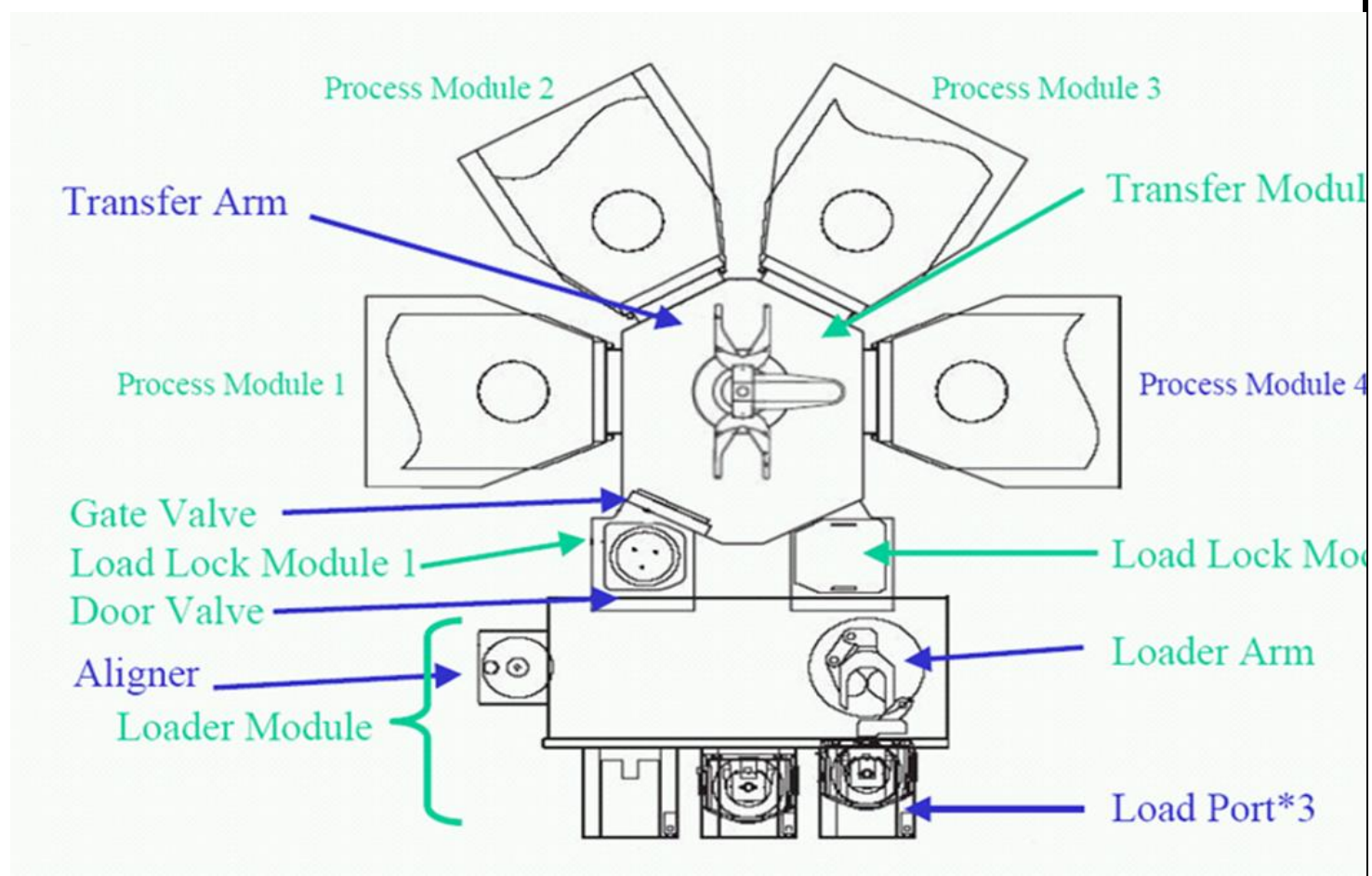


Process:	BL GL TiN Dep
Equipment ID:	TM-TB1-04
Model:	TEL Trias



S/N	Item	Maker	Model
	FI		
1	System		V1.91R1F4 PM1:V1.91R1 PM2:V1.91R1 PM3:V1.91R1 PM4:V1.91R1
2	Loadport configuration	Brooks	TLG-LON (3 Foup)
		SHINKO	SELOP12F25-30A-13
3	FI Robot	SHINKO	SBX92101286-3
	MainFrame		
4	Buffer robot	YASKAWA Electric Japan	XU-RVM4100
5	Loadlock configuration		Integrated 2-slot load blocks

6	LLM1.2 gate valve	V TEX	I-I-98009-2-1
7	Chamber gate valve	KITZ	DOUBLE ACTION
	Process Chamber : PM1		
8	Single wafer chamber with stage heater		
9	Module heater controller	RKC instrument INC	
10	Module heater controller	TEL	TMC2001
11	MFC2 CIF3 500 sccm	SAM	SFC1470FA
12	MFC3 N2 0.6/2 slm	SAM	SFC1480FAPD
13	MFC5 NH3 5 slm	SAM	SFC1481FA
14	MFC6 NH3 300 sccm	SAM	SFC1480FAPD
15	MFC7 N2 0.6/2 slm	SAM	SFC1480FAPD
16	MFC8 NH3 1 slm	SAM	SFC1480A
17	MFM TiCl4 100 sccm	STEC	SEF-8240
18	Cubic trap		
19	Regulator	Veriflo	SQ-MICRO-602PUPGPA
20	Pirani Sensor(P.SW11/12/21/32)	LEYBOLD	TSR211S
21	Pressure Sensor(PS.12/PS.31/PS.32)	PS.12/PS.32 LEYBOLD PS.31 INFICON	PS.12/PS.32 TSR211S PS.31 INFICON VSA100A
22	Capacitance Manometer(CM)	MKS	626A01TDE
23	Capacitance Manometer(1333Pa)	Leybold	CDG160A-S 1330PA
24	Capacitance Manometer(133KPa)	Leybold	CDG160A-S 133PA
25	Vapoizer(TiCl4)==>VC	STEC	VC131004ST20
	Process Chamber : PM2		
26	Single wafer chamber with stage heater		
27	Module heater controller	RKC instrument INC	
28	Module heater controller	TEL	TMC2001
29	MFC2 CIF3 500 sccm	SAM	SFC1470FA
30	MFC3 N2 0.6/2 slm	SAM	SFC1480FAPD
31	MFC5 NH3 5 slm	SAM	SFC1481FA
32	MFC6 NH3 300 sccm	SAM	SFC1480FAPD
33	MFC7 N2 0.6/2 slm	SAM	SFC1480FAPD
34	MFC8 NH3 1 slm	SAM	SFC1480A
35	MFM TiCl4 100 sccm	STEC	SEF-8240
36	Cubic trap		
37	Regulator	Veriflo	SQ-MICRO-602PUPGPA
38	Pirani Sensor(P.SW11/12/21/32)	LEYBOLD	TSR211S
39	Pressure Sensor(PS.12/PS.31/PS.32)	PS.12/PS.32 LEYBOLD PS.31 INFICON	PS.12/PS.32 TSR211S PS.31 INFICON VSA100A
40	Capacitance Manometer(CM)	MKS	626A01TDE
41	Capacitance Manometer(1333Pa)	Leybold	CDG160A-S 1330PA
42	Capacitance Manometer(133KPa)	Leybold	CDG160A-S 133PA
43	Vapoizer(TiCl4)==>VC	STEC	VC131004ST20

Process Chamber : PM3			
44	Single wafer chamber with stage heater		
45	Module heater controller	RKC instrument INC	
46	Module heater controller	TEL	TMC2001
47	MFC2 ClF3 500 sccm	SAM	SFC1470FA
48	MFC3 N2 0.6/2 slm	SAM	SFC1480FAPD
49	MFC5 NH3 5 slm	SAM	SFC1481FA
50	MFC6 NH3 300 sccm	SAM	SFC1480FAPD
51	MFC7 N2 0.6/2 slm	SAM	SFC1480FAPD
52	MFC8 NH3 1 slm	SAM	SFC1480A
53	MFM TiCl4 100 sccm	STEC	SEF-8240
54	Cubic trap		
55	Regulator	Veriflo	SQ-MICRO-602PUPGPA
56	Pirani Sensor(P.SW11/12/21/32)	LEYBOLD	TSR211S
57	Pressure Sensor(PS.12/PS.31/PS.32)	PS.12/PS.32 LEYBOLD PS.31 INFICON	PS.12/PS.32 TSR211S PS.31 INFICON VSA100A
58	Capacitance Manometer(CM)	MKS	626A01TDE
59	Capacitance Manometer(1333Pa)	Leybold	CDG160A-S 1330PA
60	Capacitance Manometer(133KPa)	Leybold	CDG160A-S 133PA
61	Vapoizer(TiCl4)==>VC	STEC	VC131004ST20
Process Chamber : PM4			
62	Single wafer chamber with stage heater		
63	Module heater controller	RKC instrument INC	
64	Module heater controller	TEL	TMC2001
65	MFC2 ClF3 500 sccm	SAM	SFC1470FA
66	MFC3 N2 0.6/2 slm	SAM	SFC1480FAPD
67	MFC5 NH3 5 slm	SAM	SFC1481FA
68	MFC6 NH3 300 sccm	SAM	SFC1480FAPD
69	MFC7 N2 0.6/2 slm	SAM	SFC1480FAPD
70	MFC8 NH3 1 slm	SAM	SFC1480A
71	MFM TiCl4 100 sccm	STEC	SEF-8240
72	Cubic trap		
73	Regulator	Veriflo	SQ-MICRO-602PUPGPA
74	Pirani Sensor(P.SW11/12/21/32)	LEYBOLD	TSR211S
75	Pressure Sensor(PS.12/PS.31/PS.32)	PS.12/PS.32 LEYBOLD PS.31 INFICON	PS.12/PS.32 TSR211S PS.31 INFICON VSA100A
76	Capacitance Manometer(CM)	MKS	626A01TDE
77	Capacitance Manometer(1333Pa)	Leybold	CDG160A-S 1330PA
78	Capacitance Manometer(133KPa)	Leybold	CDG160A-S 133PA
79	Vapoizer(TiCl4)==>VC	STEC	VC131004ST20
Subfab			
80	UPS	Fuji Electric Systems	M-UPS050J22L-UL

81	Chiller	三榮技研株式會社	TL7KCPVB-2P
82	MPD	TEL	
83	Transformer Box	TEL	Trias TB_TR2_T2

